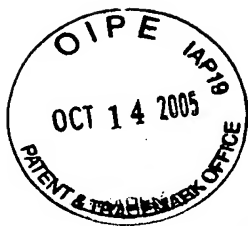


IFU



PATENT

IN THE UNITED STATES PATENT  
AND TRADEMARK OFFICE

Applicant: Hyug-Jin Kwon  
Serial No.: 10/615,062  
Filed: July 8, 2003  
Title: BATCH TYPE ATOMIC LAYER  
DEPOSITION APPARATUS  
AND IN-SITU CLEANING  
METHOD THEREOF  
Group Art Unit: 1763  
Examiner: Sylvia MacArthur  
Attorney Docket No.: 29926/39496

) I hereby certify that this paper is being  
) deposited with the United States Postal  
) Service with sufficient postage as first  
) class mail in an envelope addressed to  
) Mail Stop Amendment, Commissioner for  
) Patents, P.O. Box 1450, Alexandria,  
) Virginia 22313-1450, on **October 11,**  
) **2005.**

)   
) Sandip H. Patel (Reg. No. 43,848)  
) Attorney for Applicant

RESPONSE TO NOTICE OF NON-COMPLIANT AMENDMENT

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

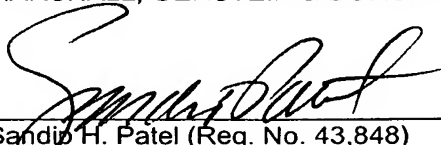
Dear Sir:

This paper is being timely submitted in response to a notice from the U.S. Patent and Trademark Office dated October 3, 2005, stating that the applicant's paper filed September 19, 2005, was not compliant with 37 CFR § 1.121 because the paper did not include the proper status identifiers for claims 1-7 and 9. In view of the notice, the applicant hereby appends to this paper a recitation of the claims with the proper status identifiers.

No fee is believed to be due.

Respectfully submitted,

MARSHALL, GERSTEIN & BORUN LLP

  
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October 11, 2005